## Paper / Subject Code: 52302 / Biomedical Microsystems

## 1T00318 - B.E.(BIOMEDICAL)(Sem VIII) (CBSGS) / 52302 - Biomedical Microsystems

Q.P. Code: 36000

(3 Hours)

Total Marks: 80

	<ul> <li>N.B.: (1) Question no. 1 is compulsory.</li> <li>(2) Answer any3 out of remaining 5 questions.</li> <li>(3) Figures on the right indicate full marks.</li> <li>(4) Assume data wherever necessary.</li> </ul>	
1.	<ul><li>(a) Discuss flow techniques in microfluidics.</li><li>(b) Discuss silicon wafer cleaning process.</li><li>(c) Explain various projection systems used in photolithography.</li><li>(d) Explain various drug delivery vehicles.</li></ul>	5 5 5 5
2.	<ul><li>(a) With the help of suitable diagrams, explain fabrication process of any one MEMS product using bulk micromachining and explain any one etch stop technique.</li><li>(b) What are cantilevers? Explain its use as a biosensor mentioning detection techniques. Discuss its fabrication with diagram at each step.</li></ul>	10 10
3.	<ul><li>(a) Discuss need of surface characterization. Discuss AFM in detail with block diagram and applications.</li><li>(b) Define soft lithography and explain micro contact printing in detail mentioning SAMs.</li></ul>	k 10 10
4.	<ul><li>(a) What is doping? Explain its type in details with advantages and shortcomings.</li><li>(b) With the help of suitable diagram explain μTAS. Also explain fabrication of any one type of micropump with neat diagram at each step.</li></ul>	10 10
5.	<ul><li>(a) Define PVD and discuss its two types in detail with neat block diagram, merits and demerits.</li><li>(b) Compare MEMS packaging with IC packaging. Discuss packaging of pressure sensor in detail.</li></ul>	10 10
5.	Write short notes on (Any four)  (a) Anisotropic Wet etching  (b) Steps of photolithography  (c) Silicon  (d) Scaling laws in fluid mechanics and electricity  (e) SOI fabrication techniques	20